

1 Surface modification and retardation of back reaction by nitrogen ion-
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4 beam treatment in dye-sensitized solar cells
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17 **Abstract**
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19 The photovoltaic performances and charge recombination of the dye sensitized solar
20 cells (DSSCs) using N-modified TiO₂ photoelectrodes were investigated under different ion-
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22 beam conditions. N-modified TiO₂ films exhibited significantly enhanced BET surface area
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24 of 92.19 m²/g with the pore volume of 0.283 cm³/g compared to the surface area of 56.65
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26 m²/g with a pore volume of 0.141 cm³/g of pristine TiO₂ film. The interstitial and
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29 substitutional affixations of nitrogen atom inside the TiO₂ lattice were confirmed by XPS and
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31 Raman spectroscopy. A 26% improvement in conversion efficiency was achieved by using
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66 *Key words:* Ion-beam, Surface modification, DSSCs, Recombination reactions, Raman

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Highlights:

- Porous channel for effective dye adsorption by N^+ ion-beam treatment
- Effectively tailored surface properties of TiO_2 film
- Retardation of charge recombination in dye sensitized solar cells
- Enhanced conversion efficiency of DSSCs by N^+ ion-beam treatment.

1. Introduction

Grätzel *et.al.* reported a photochemical solar cell using TiO₂ nanoparticle sensitized by stable Ru(II)-complex dye in 1991[1]. Due to its simplistic fabrication method and low cost, the dye-sensitized solar cell (DSSC) is proven to be one of the promising candidate for photovoltaic devices [2,3]. Recently, the highest conversion efficiency of DSSS reached at 12.3% using Co(II/III) tris(bipyridal)-based redox electrolyte in conjugation with zinc porphyrin dye [4].

It is well known that TiO₂ suffers from the oxygen deficiency with the creation of overall reduced state by forming covalent characteristic suboxides, such as TiO and Ti₂O₃. These surface defects are located in the inner band region and cause slow charge transport and higher recombination in DSSCs [5]. Plasma and ion-beam techniques were considered to be effectual surface modification methods to tailor the physical and chemical properties of metal oxide surface. The oxygen ion-beam and plasma treatment were reported to enhance the DSSC performance [6,7]. Nitrogen plasma and ion-beam modified TiO₂ films were mostly applied to investigate the photooxidation, photocatalytic conversion and photoreduction in different applications [8,9]. Recently, nitrogen incorporation in TiO₂ crystal by chemical wet method became popular for the improvement of photoconversion efficiency in DSSCs [10]. Due to the improved electrical and optical properties of N-modified TiO₂ films, it was found to be effective on photocatalytic, photovoltaic and sensor devices applications [11,12]. Nitrogen incorporation in the TiO₂ lattice by ion-beam treatment was reported to mediate methylene blue and the degradation was highly dependent on ion energy, ion fluence, irradiation time and the amount of nitrogen content [8]. However, the low energy N⁺ ion-beam treatment on TiO₂ film was not reported for DSSCs.

In this paper, we report N⁺ ion-beam as an effective treatment to replace the oxygen deficiency in TiO₂ lattice. The incorporation of nitrogen atom as a substitutional and

1 interstitial mode creates adsorption sites for higher dye uptake and retards the charge
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3 recombination as well. We suggest that N^+ ion-beam treatment is an effective
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5 physicochemical method to modify the photo electronic properties of TiO_2 surface and
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7 consequent improvement of DSSCs parameters.
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10 11 12 **2. Experimental**

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15 TiO_2 (Ti-Nanoxide D, Solaronix SA) film thickness of around $\sim 8 \mu m$ were applied on
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17 FTO glass substrate and subjected to N^+ ion-beam irradiation using a Kaufman type ion gun
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19 under the ion energy of 1000 and 1250 eV with a irradiation pressure of 2.2×10^{-4} Torr. The
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21 ion-beam current density and ion fluence was 1.5 mA/cm^2 and $\sim 10^{17} \text{ ions/cm}^2$ respectively.
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23 The ion fluence was measured using a custom-built Faraday Cup. The acceleration voltage
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25 was 100 V, and the nitrogen gas flow rate was 10 sccm. Under the above condition, the
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27 fraction of N^+ ion in the extracted beam is predominant [8].
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33 The ion-beam treated TiO_2 photoelectrodes were immersed into the dye solution (N719,
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35 Ru 535 bis-TBA, Solaronix, SA) for 24 h in the dark and subsequent rinsing with acetonitrile
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37 to remove the unanchored dyes. The dried photoelectrodes were sandwiched against a
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39 predrilled Pt sputtered counter-electrode filled with electrolyte consisting of 0.5 M LiI, 0.05
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41 M I_2 , 0.5 M 1,2-dimethyl-3-propylimidazolium iodide and 4-tertbutylpyridine 0.5 M in a
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43 mixed solvent of propylene carbonate and acetonitrile (1:4). A DSSC with untreated TiO_2
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45 film was also prepared for comparison. The surface morphology of the TiO_2 films was
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47 observed by field emission scanning electron microscopy (FE-SEM, JSM-6700, JEOL) and
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49 the XPS spectra of the TiO_2 films were obtained using ESCALAB210 (VG Scientific Ltd.,
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51 UK). Dispersive-Raman spectrum was measured by Lab RAM HR UV/Vis/NIR, Horiba
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53 JobinYvon, France. The BET specific surface area was determined by the level of nitrogen
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55 adsorption (BELSOPR II, BEL Japan) at 77 K and the pore size distribution was calculated
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1 using the Barrett, Joyner and Halenda (BJH) method. The contact angle on the TiO₂ surface
2 was measured by Phoenix 300 and the UV–Vis spectra of the adsorbed dye on the TiO₂
3 surface were obtained using a UV–Vis spectrophotometer (Hewlett Packard 8453). The
4 DSSCs were illuminated with 100 mW/cm², AM 1.5 using a 450 W Xe high power arc lamp
5 housing (LH 151, Spectral Energy Co.). The light intensity was calibrated using a
6 Radiometer Photometer (ILT1400-A). The impedance spectra were measured using
7 impedance analyzer (CH Instruments, Inc.) and scanned over the frequency range, 10⁻²-10⁵
8 Hz.
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23 3. Results and discussion

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25 Fig. 1 shows FE-SEM images of the TiO₂ film surfaces before and after N⁺ ion-beam
26 irradiation under different ion fluence. It is evident that the pristine TiO₂ film having
27 agglomerated particles can retard the effective dye adsorption on TiO₂ film. Nitrogen ion-
28 beam irradiation at 1000 and 1250 eV under the ion fluence of 2.13×10¹⁷ and 0.37×10¹⁷ ions/
29 cm² were sufficient to break the agglomerated TiO₂ particles which provide a relatively
30 porous surface, consistent with the previous results [6]. It could be suggested that under the
31 above ion-beam conditions, the critical number of ions having adequate ion-energy could
32 result in the effective morphological changes by removing the organic impurities with
33 increased porosity for better dye penetration inside the bulk of the film. However, the DSSCs
34 prepared with the ion fluence of 1.37×10¹⁷ ions/cm² at 1250 eV showed the severely etched
35 porous morphology due to the separation of weakly bonded TiO₂ particles and lower
36 conversion efficiency compared to that of 0.37×10¹⁷ ions/cm² under the same condition
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57 Fig. 2(a) shows the N 1s peak for N-modified TiO₂ film, a main peak at 399.47 eV and a
58 shoulder peak at 396.91 eV. The peak around 400 eV was mostly assigned as the interstitial
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1 incorporation of nitrogen as N–O or N–N bonding and the peak around 396 eV as the
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3 substitutional nitrogen in the form of N^{3-} ion into the TiO_2 lattice [14,15]. It suggested the
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5 successful attachment of nitrogen in TiO_2 lattice in interstitial and substitutional modes. In
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7 fig. 2(b), the Ti $2p_{3/2}$ and Ti $2p_{1/2}$ core levels appeared at 458.47, 464.28 eV for pristine and
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9 458.37, 464.04 eV for N-modified TiO_2 film. The slight peak shift to lower binding energy
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11 can be explained by the change of electron density around Ti atom due to the formation of
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13 Ti–N bond with the introduction of nitrogen in TiO_2 [15,16]. Also, a small shift of O $1s$ peak
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15 (not shown) from 529.75 to 529.59 eV was observed for N-modified TiO_2 film which could
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17 be attributed to the different atomic environment originated by nitrogen substitution inside
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19 the TiO_2 lattice [17].
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26 In Fig. 3, there are six Raman active fundamental modes at 143 (E_g), 196 (E_g), 396 (B_{1g}),
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28 516 ($A_{1g} + B_{1g}$), and 640 cm^{-1} (E_g) [18,19]. The existence of anatase phase of TiO_2 after N^+
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30 ion-beam treatment could be confirmed by three principal peaks arisen at around 396.10 cm^{-1}
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32 (B_{1g}), 515.70 cm^{-1} (A_{1g}), and 639.63 cm^{-1} (E_g). Comparing the lowest anatase characteristic
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34 peak at around 143 cm^{-1} (inset) of the untreated and the ion-beam treated sample showed
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36 significant increase of intensity, width and slight peak position shift from 142.79 to 143.16
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38 cm^{-1} which indicated the assuredly substituted nitrogen for some oxygen atoms in titania
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40 lattice [16].
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46 The hydrophilicity of N-modified TiO_2 film was investigated by water contact angle
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48 measurement. The water contact angle of the untreated TiO_2 film was 17.89°, which
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50 decreased to 9.15° upon N^+ ion-beam treatment and it was maintained even after 72 h. It
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52 suggested the retention of high surface energy of N-modified TiO_2 film for a considerable
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54 amount of time. The hydrophilic surface with low water contact angle could interact more
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56 strongly with the carboxylic groups present in the dye and result in higher dye uptake [20].
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1 Fig. 4 (a) shows the BET isotherms and pore size distributions (inset) of pristine TiO₂
2 film and N-modified TiO₂ film under different condition. BET specific surface area of
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4 film and N-modified TiO₂ film under different condition. BET specific surface area of
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6 pristine TiO₂ film was calculated to be 56.65 m²/g with a pore volume and average pore
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8 diameter of 0.141 cm³/g and 9.97 nm, respectively. After N⁺ ion-beam treatment under the ion
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10 fluence of 0.37×10¹⁷ ions/cm² at 1250 eV, the BET specific surface area of the TiO₂ film was
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12 significantly increased to 92.19 m²/g with a pore volume of 0.279 cm³/g and pore
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14 diameter of 12.12 nm. Fig. 4(b) shows the UV-Vis spectra of N719 desorbed from TiO₂
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16 photoelectrodes, dye adsorption was increased by 25.93% at 500 nm for N-modified TiO₂
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18 film under the ion fluence of 0.37×10¹⁷ ions/cm² at 1250 eV. The higher dye adsorption is
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20 related to the presence of N³⁻ ion in the TiO₂ lattice which can oxidize the Ti³⁺ center to Ti⁴⁺.
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22 The higher charge on Ti was expected to interact more strongly with the carboxylic group of
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24 dye [21].
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31 Fig. 5(a) shows the photocurrent–voltage characteristics of the DSSCs based on the
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33 pristine and N-modified TiO₂film at 1000 and 1250 eV. N-modified DSSCs showed only 10
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35 mV increase of open circuit voltage (V_{oc}'s) which may be related to the similar band gap even
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37 after N³⁻ incorporation in TiO₂ lattice [22]. But significant increase of short circuit current
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39 (J_{sc}) were observed after N⁺ ion-beam treatment from the initial value of 11.88 to 14.57 mA/
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41 cm². The increased short circuit density (J_{sc}) was related to higher dye uptake as result of
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43 physicochemical modification of TiO₂ surface by N⁺ ion-beam treatment. No significant
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45 change in fill factors (FF) was observed after N⁺ ion-beam treatment on photoanode. Also,
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47 DSSCs prepared by N-modified TiO₂ photoelectrode under the ion fluence of 0.37×10¹⁷ ions/
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49 cm² at 1250 eV reached the maximum conversion efficiency up to 6.96% from 5.53% of
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51 the pristine one.
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1 The significantly increased radius of the mid-semicircle regime in Fig. 5(b) resembles
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3 the augmented surface resistance of TiO₂ photoelectrode and suppressed back-transfer of
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5 photogenerated electrons of N-modified TiO₂ films to the electrolyte at TiO₂/dye/electrolyte
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7 interface. From Bode phase plots, increased amplitude and electron lifetime were also
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9 observed. The DSSCs prepared under the ion fluence of 0.37×10^{17} ions/cm² at 1250 eV
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11 showed lower charge recombination and higher electron lifetime from 34.84 to 39.51 ms
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13 compared to pristine TiO₂. N⁺ ion-beam treated DSSCs also showed suppressed production
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15 of dark current compare to untreated one. It is evident that when a negative potential is
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17 applied between the photoanode and counter electrode, the electrons are forced to transfer
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19 and trapped by different pathways. Figure (S.1) illustrates the comparative dark current of
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21 DSSCs based on N⁺ ion-beam treated and untreated TiO₂ photo electrodes. The N⁺ ion-beam
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23 treated DSSCs exhibit smaller dark current, which indicates that nitrogen incorporation could
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25 successfully retard the charge recombination at TiO₂/dye/electrolyte interface. Thus,
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27 the bond O–Ti–N, formed by N⁺ ion-beam treatment could effectively inhibit the reduction
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29 of I³⁻ on the TiO₂ electrode [17].
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37 The surface defects originated from the oxygen deficiency in TiO₂ lattice lead to the
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39 formation of paramagnetic center which act as a trap sites for photogenerated electrons in
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41 TiO₂ surface [23]. N⁺ ion-beam treatment introduces N as a preferred state of N³⁻ inside the
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43 lattice which can oxidize the reduced state of Ti³⁺ to Ti⁴⁺ by filling the N-2p state [24]. This
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45 causes the depletion of the Ti 3d state and removes the trapping centers for photogenerated
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47 electrons [22]. The surface modification of TiO₂ films by N⁺ ion-beam treatment improved
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49 the surface properties, electron lifetime, and retardation of charge recombination in DSSCs.
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57 **4. Conclusions**

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1 N⁺ ion-beam treatment was employed to increase the surface area and porosity of TiO₂
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3 film and to reduce the charge recombination of DSSCs. XPS and Raman spectra revealed the
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5 presence of nitrogen inside the TiO₂ lattice as interstitial and substitutional states. It is
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7 speculated that the introduction of nitrogen as N³⁻ ion replaced the oxygen deficiencies in the
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9 TiO₂ lattice and lead to the smaller number of surface defects. Electrochemical impedance
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11 spectroscopy results indicated the appreciable decrease in recombination reaction after N⁺
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13 ion-beam treatment. The effective reduction of surface defects resulted in lesser
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15 recombination and longer electron lifetime in DSSCs. We found the increase of photo-
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17 conversion efficiency by 26% which is quite significant for the development of high
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19 performance DSSCs. This paper demonstrates the effectiveness of the N⁺ ion-beam treatment
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21 to tailor the defect sites, surface properties and the consequent improvement of DSSCs
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23 performance.
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Table 1Characteristics of the DSSCs with the pristine and N-modified TiO₂ photoelectrodes.

TiO ₂ films	Ion fluence ($\times 10^{17}$ ions/cm ²)	Dye adsorbed ($\times 10^{-5}$ mol/cm ²)	V_{oc} (V)	J_{sc} (mA/cm ²)	FF (%)	η (%)
Untreated	-	3.78	0.73	11.88	63.71	5.53
Ion-beam energy (1000 eV)	1.07	4.29	0.73	12.12	64.34	5.71
	2.13	4.41	0.74	13.99	65.05	6.75
Ion-beam energy (1250 eV)	0.37	4.76	0.74	14.57	64.55	6.96
	1.37	4.43	0.73	12.44	63.06	5.70

1 **Figure Captions**
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6 **Fig. 1.** Field emission scanning electron microscopy images of (a) pristine, (b) 1000 eV
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8 (2.13×10^{17} ions/cm²), and (c) 1250 eV (0.37×10^{17} ions/cm²) N⁺ ion-beam treated TiO₂ film
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15 **Fig. 2.** XPS spectrum of (a) N 1s peak of N-modified and (b) Ti 2p of pristine and modified
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17 TiO₂ films.
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22 **Fig. 3.** Raman spectra of full length and expanded for E_g mode (inset) at 143 cm⁻¹ of pristine
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24 and N-modified TiO₂ film.
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29 **Fig. 4.** (a) Nitrogen gas adsorption-desorption isotherm and pore size distribution (inset) and
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31 (b) absorption spectra of N719 dye desorbed from untreated and ion-beam treated TiO₂ films.
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37 **Fig. 5.** (a) *J-V* characteristic curve (b) Nyquist plots for DSSC based on pristine and N-
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39 modified TiO₂ photoelectrodes.
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Figure 1
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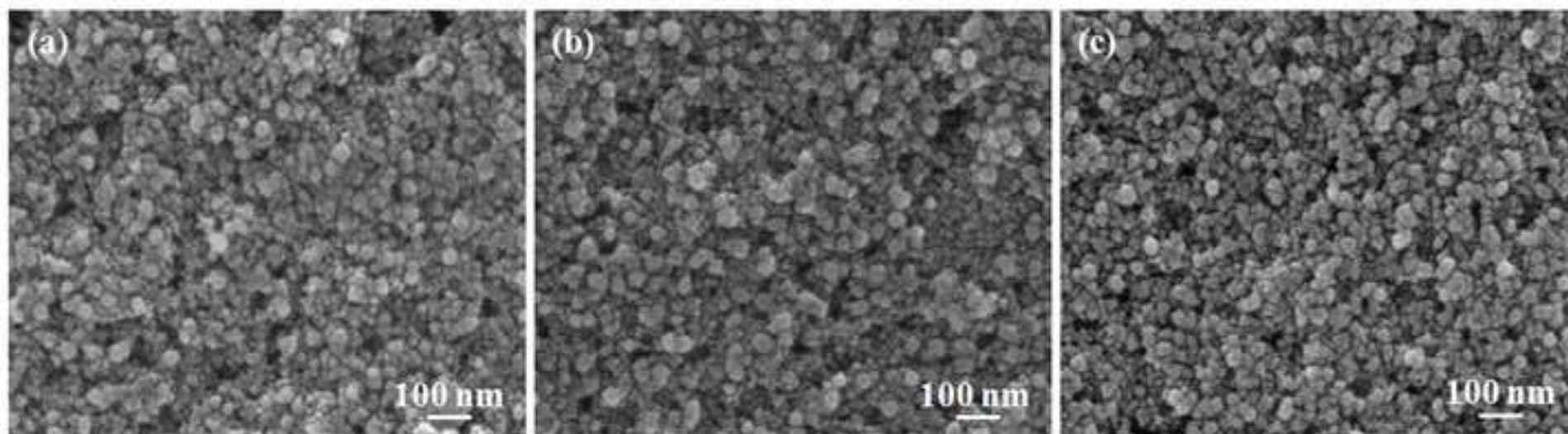


Figure 2
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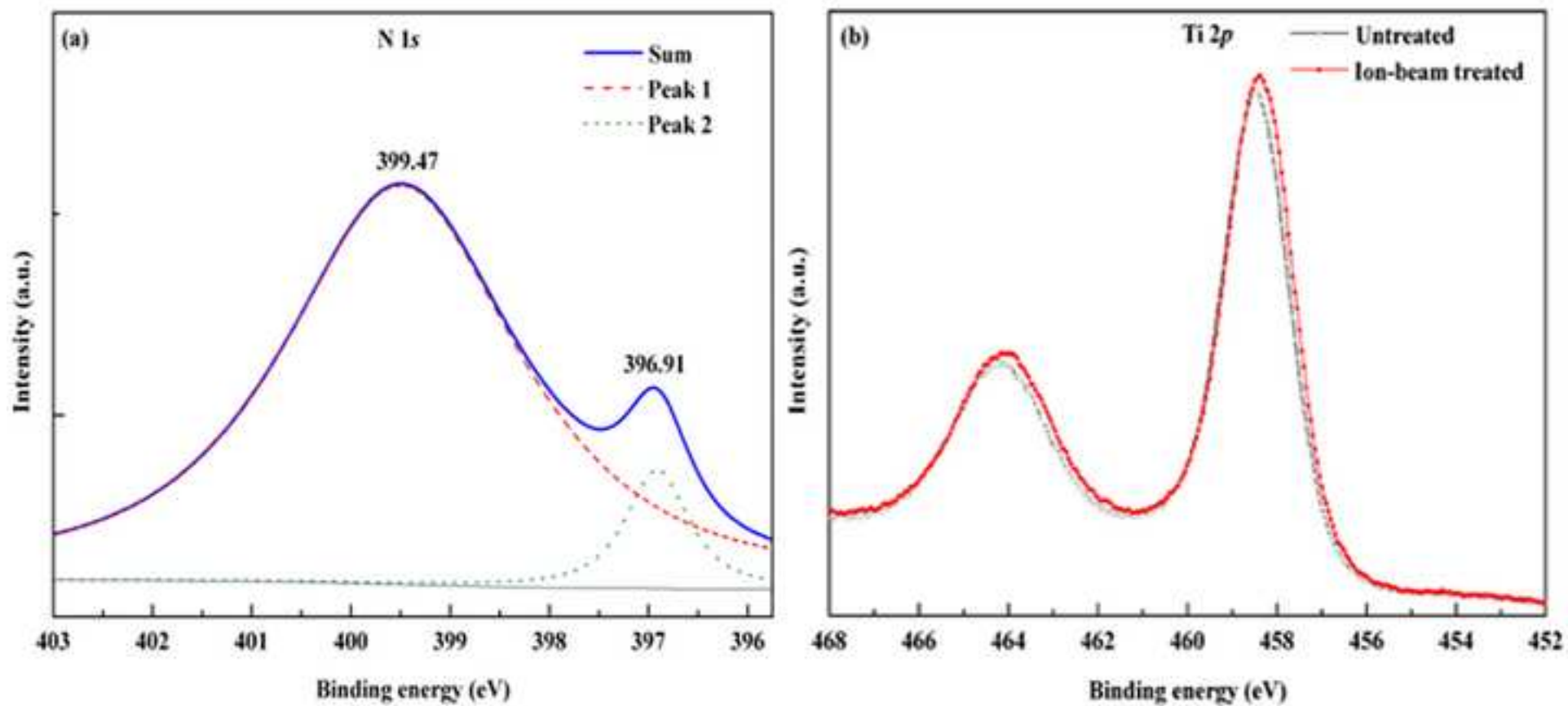


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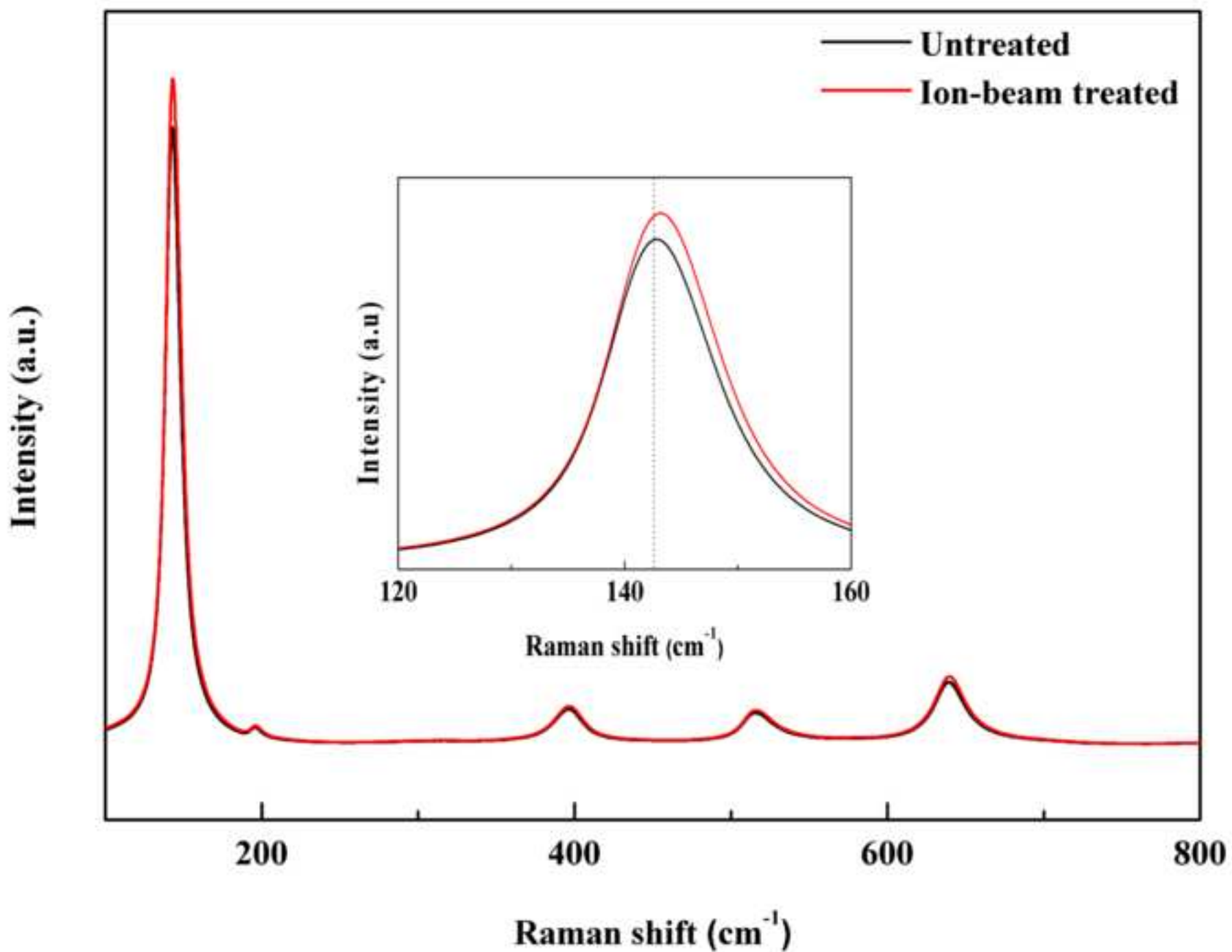


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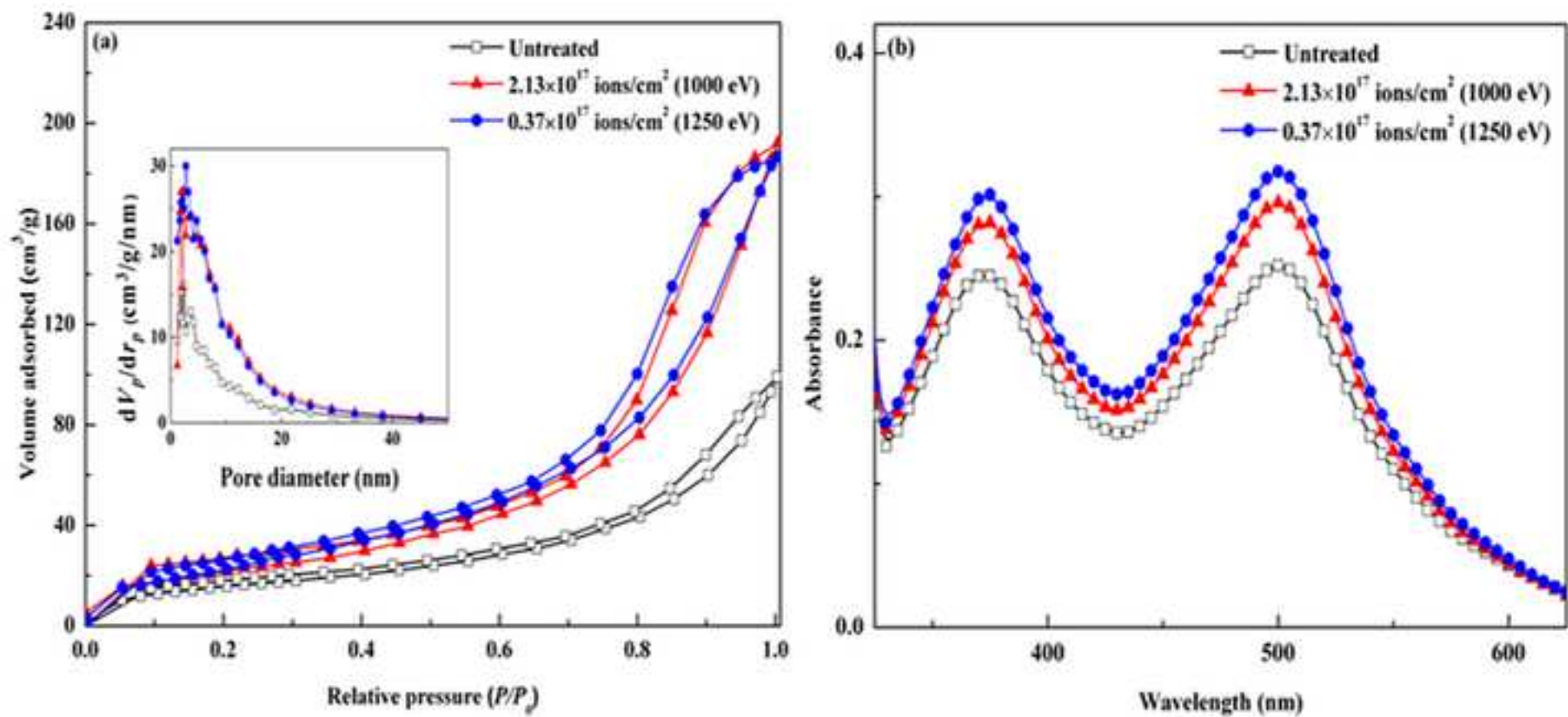


Figure 5
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